Japan TC Chapter of
Automation Technology Global Technical Committee
Meeting Summary and Minutes

Japan Standards Fall 2014 Meetings
Thursday, September 25, 2014, 1:30 p.m. – 5:00 p.m.
SEMI Japan office, Tokyo, Japan

Next Committee Meeting
Tuesday, December 9, 2014, 1:30 p.m. – 5:00 p.m. <Japan Standard Time>
Japan Standards Winter 2014 Meetings, Tokyo

Committee Announcements (optional)
None

Table 1 Meeting Attendees

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Daihen</td>
<td>Otogawa</td>
<td>Yasunobu</td>
<td>Tokyo Electron</td>
<td>Asakawa</td>
<td>Terry</td>
</tr>
<tr>
<td>Mitsubishi Electric</td>
<td>Sambu</td>
<td>Ken</td>
<td>Tokyo Electron</td>
<td>Murata</td>
<td>Naoko</td>
</tr>
<tr>
<td>Nisshinbo Mechatronics</td>
<td>Ishikawa</td>
<td>Makoto</td>
<td></td>
<td></td>
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</tr>
<tr>
<td>Siemens</td>
<td>Ohbuchi</td>
<td>Fumiyasu</td>
<td>SEMI Japan</td>
<td>Yanagisawa</td>
<td>Chie</td>
</tr>
</tbody>
</table>

*alphabetical order by company name

Table 2 Leadership Changes
None

Table 3 Ballot Results (or move to Section 4, Ballot Review)

**Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review. **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting.

<table>
<thead>
<tr>
<th>Document #</th>
<th>Document Title</th>
<th>Committee Action</th>
</tr>
</thead>
<tbody>
<tr>
<td>5697A</td>
<td>Line Item Revisions to SEMI PV35-0414, Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System</td>
<td></td>
</tr>
<tr>
<td>5698A</td>
<td>Line Item Revision to SEMI PV35.1-0114, Media Interface Specifications for A Horizontal Communication between Equipment</td>
<td></td>
</tr>
</tbody>
</table>

Table 4 Authorized Ballots (or move to Section 7, New Business)
None
1 Welcome, Reminders, and Introductions

Makoto Ishikawa (Nisshinbo Mechatronics) called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

| Motion: | To approve the previous meeting minutes written as it is. |
| By / 2nd: | Ken Sambu (Mitsubishi Electric) / Naoko Murata (Tokyo Electron) |
| Discussion: | None |
| Vote: | 4 in favor and 0 opposed. Motion Passed. |

3 Liaison Reports

3.1 Europe TC Chapter

There is no report.

3.2 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. Of note:

- PV Automation TC Transformation to Automation Technology TC
- Guidance for Task Force Meeting Management
- SEMICON Japan 2014 to be held at Tokyo Big Sight from December 3 to December 5.

Attachment: 01_SEMI Staff Report 2014 September_R0.3 and 02_Guidance for Task Force Meeting Management (TF Leaders)
4 Ballot Review

4.1 Document #5697A: Line Item Revision to SEMI PV35-0414, “Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System”

4.1.1 Line Item #1: Byte order on communication line is not specified precisely but recommended as endian, and it causes mismatch between different equipment suppliers. This Standard shall specify valuable data and define how to align data, but shall not define byte order. Byte order shall be defined by PV35.1. Accordingly, delete section 7.3.5.

This Line item passed committee review as balloted. The details are described in the attached #5697A Procedural Review Voting Sheet.

Attachment: 03_5697A_ProceduralReview_Final

4.2 Document 5698A: Line Item Revision to SEMI PV35.1-0114, “Media Interface Specifications for a Horizontal Communication between Equipment”

4.2.1 Line Item #1: The definition how to connect and maintain sessions of TCP are not specified. Revise the following items accordingly.

This Line item passed committee review as balloted. The details are described in the attached #5698A Procedural Review Voting Sheet.

Attachment: 04_5698A_ProceduralReview_Final

5 Subcommittee & Task Force Reports

5.1 Equipment Interface Specification (EIS) Task Force

Makoto Ishikawa (Nisshinbo Mechatronics) reported for the Equipment Interface Specification (EIS) Task Force.

• The Revised TFOF and Revised SNARFs were approved by GCS on September 24, 2014
  o TFOF for Global Equipment Interface Specification (EIS) TF
  o #5697 SNARF for Line Item Revisions to SEMI PV35-0114, “Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System”
  o #5698 SNARF for Line Item Revisions to SEMI PV35.1-0114, “Media Interface Specifications for a Horizontal Communication between Equipment”

6 Old Business

None

7 New Business

7.1 Future activity

Terry Asakawa (Tokyo Electron) addressed the committee on this topic. He stated that to supply in package would be very significant in order that Standards of this area to be widely used, which is quite different from standardization of semiconductor industry. Therefore, it will have been very important for this activity to have liaison with FlowMasterForum.

He also continued that the activity of FlowMasterForum has been in a slowdown with the stagnation of PV industry. Now, PV Automation Committee has been transformed to Automation Technology Committee, so that Automation Technology Committee could have a strong relationship with FlowMasterForum.
8 Action Item Review

8.1 Open Action Items
Chie Yanagisawa (SEMI Japan) reviewed the open action item. This can be found in the Open Action Items table at the beginning of these minutes.

8.2 New Action Items
None

9 Next Meeting and Adjournment
The next meeting of the Japan TC Chapter of Automation Technology Global Technical Committee is scheduled for 1:30 p.m. – 5:00 p.m., Tuesday, December 9 at Japan Standards Winter 2014 Meetings at SEMI Japan office in Tokyo.
Respectfully submitted by:
Chie Yanagisawa
Senior Standard Coordinator
SEMI Japan
Phone: +81.3.3222.5863
Email: cyanagisawa@semi.org

Minutes approved by:
Makoto Ishikawa (Nisshinbo Mechatronics), Co-chair  September 25, 2014
Ken Sambu (Mitsubishi Electric), Co-chair  September 25, 2014
Terry Asakawa (Tokyo Electron), Co-chair  September 25, 2014

Table 8 Index of Available Attachments #1

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<th>#</th>
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<tr>
<td>02</td>
<td>Guidance for Task Force Meeting Management (TF Leaders)</td>
<td>04</td>
<td>5698A_ProceduralReview_Final</td>
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</tbody>
</table>

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.